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PR	DD 234 941(A1)	4-16-86	Schöedel et al.	G01		/10	Yes X	No_	
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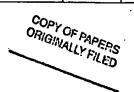
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EQ.	3,431,077	3/04/69	Danforth	23	253	7/18/66
EQ	3,536,452	10/27/70	Norton et al.	23	259	12/10/62
EU	4,099,923	7/11/78	Milberger	23	254 R	1/17/77
. EQ	4,705,669	11/10/87	Tsuji et al.	422	93	8/27/86
EQ.	4,869,282	9/26/89	Sittler et al.	137	15	12/09/88
. LQ	4,996,387	2/26/91	Gerhold et al.	585	654	7/20/89
ER	5,089,232	2/18/92	May	422	83	1/24/90
P.Q	5,252,294	10/12/93	Kroy et al.	422	102	2/03/92
PD	5,304,354	4/19/94	Finley et al.	422	196	11/30/92
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ED.	5,593,642	1/14/97	DeWitt et al.	422	131	6/05/95
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ER	5,658,537	8/19/97	Dugan	422	191	7/18/95
1/17	5,690,763	11/25/97	Ashmead et al.	156	60	6/06/95
70	5,750,906	5/12/98	Parker et al.	73	863.73	10/29/96
RQ	5,776,359	7/07/98	Schultz et al	252	62.51	5/08/95
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EU	5,811,062	9/22/98	Wegeng et al.	422	129	2/23/96
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ATTORNEY'S DOCKET NO .: **APPLICATION NO.:** INFORMATION DISCLOSURE 2000-022DIV1 09/801.389 **CITATION** PTO-1449 APPLICANT: Bergh et al. FILING DATE: GROUP: 3/7/2001 1743 FOREIGN DOCUMENTS **EXAMINER'S** PATENT NO. COUNTRY DATE **CLASS** SUB TRANSLATION INITIALS **CLASS** YES NO EP 0 796 654 A2 9/24/97 **EPO** B01J 19/00 EP 0 886 143 A1 12/23/98 **EPO G01N** 33/68 WO 96/15576 5/23/96 PCT H02K 44/02 WO 97/32208. 9/04/97 PCT **G01N** 31/10 WO 98/00231 1/08/98 PCT **B01J** 19/00 WO 98/03521 1/29/98 PCT C07F 19/00 WO 98/07026 2/19/98 PCT **G01N** 31/10 X WO 98/13137 4/02/98 PCT **B01J** 19/00 WO 98/13605 4/02/98 PCT F15C 5/00 WO 98/16949 4/23/98 PCT H01J 49/40 X WO 98/22811 5/28/98 PCT **G01N** 27/26 WO 98/53236 PCT 11/26/98 F16K 31/126 WO 98/55852 12/10/98 PCT **G01N** 27/26 WO 98/56505 12/17/98 PCT B₀₁L 3/00 WO 99/41005 PCT 8/19/99 **B01J** 19/00 X WO 99/64160 PCT 12/16/99 B01L 3/02 WO 00/09255 2/24/00 PCT **B01J** 19/00 WO 00/14529 3/16/00 PCT **G01N** 31/02 WO 00/17413 PCT 3/30/00 C23C 14/04 WO 00/51720 9/08/00 PCT B01J 19/00 WO 01/00315 1/04/01 PCT **B01J** 19/00 OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages etc.) Berenschot, J.W., et al., "Micromachining of {111} Plates in <001> Oriented Silicon", J. Micromech. Microeng. 8 (1998) 104-107 Brenchley, D.L. et al, "Status of Microchemical Systems Development in the United States of America", AICHE, 2nd International Conference on Microreaction Technology, New Orleans, Louisiana, March 9-12, 1998, pp. 18-23 Bruns, M.W., "Th Application of Silicon Micromachining T chnology and High Speed Gas Chromatography to On-Lin Process Control", MTI Analytical Instruments Bruns, M.W., "Silicon Micromachining and High Speed Gas Chromatography", IEEE, 1992, pp. 1640-1644

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